

PATENT

Atty. Docket No.: 006915 USA P02/FEP/P3I/PJT  
RW Ref. No.: APM/001-02-CP1-2

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: )  
Kenneth Collins, et al. )  
 )  
Entitled: PLASMA IMMERSION ION ) Group Art Unit: 2893  
IMPLANTATION APPARATUS USING A )  
PLASMA SOURCE HAVING LOW )  
DISSOCIATION AND LOW MINIMUM PLASMA )  
VOLTAGE )  
 ) Examiner: Jack S. Chen  
Application Serial No.: 10/646,533 )  
 )  
Application Filing Date: )  
08/22/2003 )

LETTER TO THE EXAMINER


Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Attached please find a copy of an official action issued in a related application already of record in the present application (official action dated 11/25/2009 in Appln. Serial No. 11/600,680).

Respectfully submitted,

Dated 12/04/09

  
Robert M. Wallace  
Attorney for Applicants  
Reg. No. 29,119  
Customer No. 000044843

Robert M. Wallace  
Law Office of Robert M. Wallace  
2112 Eastman Avenue, Suite 102  
Ventura, CA 93003  
(805) 644-4035